MOCVD growth of MgGa₂O₄ thin films for high-performance solar-blind UV photodetectors

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ABSTRACT

Epitaxial MgGa₂O₄ thin films with a bandgap of 5.18 eV were grown on the *c*-plane sapphire substrate by using metal organic chemical vapor deposition. The structure, optical, electronic, and optoelectronic properties of MgGa₂O₄ thin films have been investigated before and after high-temperature annealing in an oxygen or nitrogen atmosphere. In particular, the O₂-annealed MgGa₂O₄ thin film reveals a high crystalline quality and a low concentration of oxygen vacancies. Moreover, a quick response speed ($t_r = 20 \text{ ns}, t_d = 400 \text{ ns}$), a low dark current (~17 pA at 10 V), and a high UV/Visible rejection ratio (>10⁵) can be demonstrated in the O₂-annealed MgGa₂O₄ photodetector, indicating the excellent solar-blind ultraviolet (SBUV) photodetection characteristics. The effect of annealing atmosphere on the photoelectric properties of the film and its physical mechanism were studied. This research provides an effective way to realize high-performance SBUV photodetectors and opens up the application of MgGa₂O₄ spinel in the field of semiconductor optoelectronic and microelectronic devices.

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Solar-blind ultraviolet (SBUV) photodetectors have attracted much attention due to their inherent advantages of low background noise, high sensitivity, and strong anti-interference ability, which have broad potential applications in both military and civilian fields.¹⁻³ Until now, various wideband gap (WBG) semiconductors (such as GaAlN,^{4–6} ZnMgO,^{7,8} and Ga₂O₃^{$\tilde{9}$ –11}) have been used to demonstrate the SBUV photodetectors, and some of them have yielded amazing performance. However, the fabrication of high-quality GaAlN^{5,12} and ZnMgO^{13,14} ternary alloy films usually require harsh conditions, which brings a huge challenge for the development of highperformance SBUV detectors. Meanwhile, multiple deep level defect states within the bandgap are easily formed in Ga2O3 and, thus, slow response speed and small UV/Visible rejection ratio have become common problems of Ga₂O₃ SBUV photodetectors.⁷ Fortunately, the exploration of materials for preparing high-performance solar-blind photodetectors has never ceased. In recent years, ternary complex oxide WBG semiconductors, such as ZnGa₂O₄,^{15,16} Zn₂GeO₄,¹⁷ and

In₂Ge₂O₇,¹⁸ have been intensively studied for SBUV detection because of their ideal bandgap, tunable properties via adjusting the components, high chemical and physical stability, and so on. Among them, spinel ternary oxide MgGa₂O₄ semiconductor, with large optical bandgap of 4.7–5.36 eV at room temperature, has good mechanical properties, high thermo-chemical stability at high temperature and high radiation hardness, making it suitable for SBUV photodetector application.^{19–23}

However, MgGa₂O₄ was well known as a good luminescence material, and the luminescence properties of MgGa₂O₄ doped with Mn, Cr, Eu, and Ni have been intensively investigated to realize green, red, or near-infrared light emission under specific light irradiation.^{23–26} Recently, the breakthrough in the fabrication of bulk MgGa₂O₄ single crystals has promoted its research and application as a transparent semiconductor oxide and an epitaxial substrate.²⁰ At the same time, owing to the excellent electrical and optical characteristics, MgGa₂O₄ has been regarded as an emerging semiconductor for high performance devices.^{18,19} However, only very few MgGa₂O₄-based semiconductor devices, including gas sensors²⁷ and spintronic devices,^{22,28} have been reported so far. No information is available about optoelectronic devices based on MgGa₂O₄, including a SBUV photodetector.

In this study, we report on the epitaxial growth of MgGa₂O₄ films by metal organic chemical vapor deposition (MOCVD) and the properties of their metal–semiconductor–metal (MSM) SBUV photodetectors. The structural, optical, and morphological properties of the films have been investigated before and after annealing in oxygen (O₂) or nitrogen (N₂) atmosphere. Additionally, the effect of hightemperature annealing of MgGa₂O₄ films on the performance of the SBUV detectors was also studied. Clearly, compared with devices based on as-grown and N₂-annealed thin films, the SBUV detector based on the O₂-annealed MgGa₂O₄ film has the lowest leakage current (~17 pA at a bias of 10 V) and the fastest response speed (t_r = 20 ns, t_d = 400 ns). The detailed mechanism for this phenomenon was subsequently discussed. Our findings in this work suggest that MgGa₂O₄ is an ideal candidate material for SBUV detection and has broad application prospects.

MgGa₂O₄ thin films were grown on *c*-plane sapphire substrates by MOCVD. Biscyclopentadienyl-Mg (Cp₂Mg), triethylgallium (TEGa), and high-purity oxygen gas were used as the magnesium, gallium, and oxygen precursors, respectively. High-purity nitrogen gas was selected as the carrier gas. The thin films were grown under a substrate temperature of 650 °C with a chamber pressure of 3000 Pa. The flow rates of Cp₂Mg, TEGa, and oxygen were kept at 10, 2, and 200 sccm, respectively. After the growth, MgGa2O4 films were annealed at a temperature of 900 °C in an O₂ or N₂ atmosphere for 1 h. The optical, structural, and surface morphology properties of MgGa₂O₄ films were characterized by adopting an UV-3101 PC scanning spectrophotometer, a Bruker D8GADDS x-ray diffractometer (XRD), and a scanning electron microscope (SEM) (HITACHI S-4800). Qualitative and quantitative analyses of the elements of the films were characterized by X-ray Photoelectron Spectroscopy (XPS) (Thermo ESCALAB 250). To further investigate the SBUV photodetection performance of the MgGa₂O₄ films with and without annealing, Au interdigital electrodes were fabricated on the films by photolithography and liftoff technology, thus realizing MgGa₂O₄ MSM photodetectors. The current–voltage (I-V) characteristic curves and time-dependent photocurrent (I-t) curves of the devices were measured by a semiconductor device analyzer (Agilent B1500A). The measurements of transient response characteristic and spectral response characteristic were carried out by using an oscilloscope, a Nd: YAG laser (245 nm), and a 200 W UV-enhanced Xe lamp with a monochromator.

Figure 1(a) shows the XRD patterns of as-grown, N₂-annealed, and O₂-annealed MgGa₂O₄ thin films on the *c*-face sapphire substrate. The strong and sharp peak that presents at $2\theta = 41.68^\circ$ can be indexed as a (0006) peak of the *c*-Al₂O₃ substrate. In addition, all samples have three weak diffraction peaks at about $2\theta = 18.6^{\circ}$, 37.8° , and 58° , which correspond exactly to the (111), (222), and (333) diffraction planes of the spinel MgGa₂O₄ (JCPDS No. 73-1721), respectively. It indicates that the MgGa₂O₄ films have a preferred growth orientation along the [111] direction. In addition, there is almost no change in the position of the diffraction peak after annealing. To further investigate the crystalline quality of MgGa₂O₄ films with and without annealing, high resolution XRD measurements have been performed as shown in Fig. 1(c). The full width at half maximum (FWHM) of the MgGa₂O₄ (222) peak of XRD rocking curve was estimated to be 0.15885°, 0.05068°, and 0.04191° for the as-grown, $O_2\text{-annealed},$ and $N_2\text{-annealed}$ thin films, respectively. According to the previous reports, the high temperature annealing can help the lattice atoms to obtain enough energy to migrate to the appropriate position and can release the stress and reduce the dislocations and grain boundaries in the films.^{29,30} Therefore, the decrease in the FWHM indicates that the crystalline quality could be significantly improved by the post-annealing at high temperature both in N2 and O2 atmospheres.

Figures 2(a), 2(b), and 2(c) present the top-view and the cross-sectional view SEM images of as-grown, O₂-annealed, and N₂-annealed MgGa₂O₄ thin films, respectively. It can be seen that all three films exhibit a granular surface morphology with a thickness of \sim 200 nm.

The optical transmission spectra of the MgGa₂O₄ films with and without annealing are shown in Fig. 2(d). The as-grown MgGa₂O₄ film exhibits an average transmittance of ~75% in the wavelength range from 300 to 700 nm. After high temperature annealing in N₂ and O₂ atmospheres, the average transmittance of the samples for the 300–700 nm wavelength range increases obviously to ~85%. In



FIG. 1. (a) XRD patterns and (b) normalized XRD rocking curves of (222) plane of $MgGa_2O_4$ films with and without annealing.





addition, a sharp absorption edge can be observed at \sim 240 nm for all three samples, corresponding to an optical bandgap of \sim 5.18 eV as shown in the inset of Fig. 2(d).

According to the previous reports, the oxygen vacancy defects in the oxide semiconductors strongly affect their optical, electrical, and optoelectrical properties.^{31,32} To investigate the chemical states and element composition of the MgGa₂O₄, XPS measurement was performed and the high resolution O1s XPS spectra were collected for MgGa₂O₄ films with and without annealing as shown in Fig. 3. The photoelectron energy scale was calibrated using C1s line at 284.6 eV. Obviously, the O1s peak can be consistently fitted by two near Gaussian components, centered at about 530.5 eV (O_I) and 531.8 eV (O_{II}), which are related to lattice oxygen (O^{2–}) and oxygen vacancies $\rm (V_o),$ respectively.^{27,33} As can be observed, the relative ratios of the $\rm O_{II}$ peaks of as-grown, O₂-annealed, and N₂-annealed MgGa₂O₄ films are 30.64%, 15.21%, and 34.06%, respectively. This result clearly indicates that the concentration of oxygen vacancies in MgGa₂O₄ decreased after annealing in oxygen atmosphere. In contrast, high-temperature N₂ annealing could result in a slight increase in the V_o content.

In order to further study the UV detection performance of MgGa₂O₄ films, the MSM SBUV detectors with 25 pairs of Au interdigital electrodes (50 nm thickness) were fabricated using conventional photolithography and liftoff technology as shown in Fig. 4(a). The finger width and spacing of the interdigital electrodes are both 10 μ m with a length of 1 mm. The *I*–*V* characteristics of the MgGa₂O₄ SBUV photodetectors measured in the dark are depicted in Fig. 4(b). The



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FIG. 4. (a) Schematic illustration of the SBUV MSM PDs based on MgGa₂O₄ films. (b) Dark *I*-*V* curves of MgGa₂O₄ SBUV PDs. (c) The spectral response of the SBUV PDs under 10 V bias with y axis in logarithmic scale.

Schottky contacts were formed between the MgGa₂O₄ film and the Au electrodes. Under 10 V bias, the dark currents of the devices based on as-grown, O2-annealed, and N2-annealed MgGa2O4 films are 54, 17, and 106 pA, respectively. Since oxygen vacancies are typical donor defects, the difference in the dark current should be related to the concentration of oxygen vacancies in MgGa₂O₄ films.²⁰ Figure 4(c) represents the spectral response of the MgGa₂O₄ SBUV PDs at a bias of 10 V. Notably, a very small responsivity of only several μ A/W can be observed in the wavelength range of 225-270 nm for the as-grown MgGa₂O₄ photodetector. In contrast, the N₂-annealed and O₂annealed devices show a large peak responsivity of about 1.84 and 0.23 A/W at \sim 248 nm with a -3 dB cutoff wavelength of \sim 255 nm, respectively. The higher responsivity of N2-annealed MgGa2O4 may be associated with the trapping of photo-generated holes at neutral oxygen vacancies, which leads to a photoconductive gain. In addition, the O2-annealed device possesses the higher UV-Vis rejection ratio $(R_{peak}/R_{400\,nm})$, which is more than 5 orders of magnitude. This phenomenon can be attributed to the large reduction of oxygen vacancy defects in MgGa₂O₄ after O₂ annealing, because oxygen vacancies often cause visible light absorption and response.

The *I*-*t* characteristics curves were measured by periodically turning on and off 254 nm (light intensity $500 \,\mu$ W/cm²) light at a bias of 10 V. As shown in Fig. 5(a), the as-grown MgGa₂O₄ SBUV PD shows a weak response to the 254 nm light with poor stability and reproducibility. After annealing, the photocurrent of the devices

significantly increased, and a good repeatability can be clearly observed [see Figs. 5(b) and 5(c)]. More interestingly, under (500 μ W/cm²) 254 nm light illumination at 10 V bias, the light-to-dark current ratio (I_{light}/I_{dark}) is as high as ~1 × 10⁶ for the O₂-annealed MgGa₂O₄ photodetector, while I_{light}/I_{dark} of the as-grown and N₂-annealed devices are ~1.1 and ~5 × 10⁵, respectively.

To further investigate the response speed of the devices, the transient photoresponse measurement was carried out using a Nd:YAG pulsed laser with a wavelength of 245 nm. The laser pulse width and the frequency are 10 ns and 10 Hz, respectively. As shown in Figs. 6(a) and 6(c), both O₂-annealed and N₂-annealed MgGa₂O₄ SBUV photo-detectors have a very fast, highly stable, and reproducible response to the SBUV light. The 10%–90% rise time and 90%-10% decay time of O₂-annealed device are around 20 and 400 ns, respectively, as shown in Fig. 6(b). As for N₂-annealed device, its 10%–90% rise time and 90%-10% decay time are around 80 ns and 30 μ s, respectively. Notably, in Fig. 6(d), the decay portion of the transient response exhibits two distinct phases: a fast initial decay followed by a much slow decay. The slow decay should be associated with large amounts of oxygen vacancy defects in MgGa₂O₄ after annealing in N₂ atmosphere.

In summary, we have demonstrated the spinel ternary oxide $MgGa_2O_4$ thin films on the *c*-plane sapphire substrate using MOCVD. After post annealing in O_2 or N_2 atmosphere, the crystalline quality of $MgGa_2O_4$ thin films was improved obviously. The O_2 -annealed $MgGa_2O_4$ film has a lower oxygen vacancy defect concentration



FIG. 5. *I–t* characteristics of (a) as-grown, (b) O₂-annealed, and (c) N₂-annealed MgGa₂O₄ SBUV photodetectors under 254 nm light illumination with an intensity of 500 μ W/ cm² at 10 V.





compared to the as-grown and N₂-annealed samples. In addition, an excellent SBUV photodetection performance has been observed for O₂-annealed MgGa₂O₄ film. The dark current of the MSM SBUV photodetector based on O₂-annealed MgGa₂O₄ was only about 17 pA at a bias of 10 V, and the peak responsivity was 0.23 A/W at ~248 nm with a -3 dB cutoff wavelength of ~255 nm. In addition, the UV-Vis rejection ratio (R_{peak}/R_{400 nm}) is more than 5 orders of magnitude, which may be related to the suppression of visible light response by the reduction of defects after oxygen annealing. Our findings in this work indicate that MgGa₂O₄ spinel is a promising candidate for realizing high-performance SBUV photodetection.

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AUTHOR DECLARATIONS

Conflict of Interest

The authors have no conflicts of interest to disclose.

DATA AVAILABILITY

The data that support the findings of this study are available from the corresponding author upon reasonable request.

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